

一、 The Configurations of Semi-Automated Recovery System of Nano Contaminants (SC Series)

- Obtained International Patent for bevel recovery.
 - The world's top-class function and technology in collecting hydrophilic surface.
 - High-performance equipment to collect nano contamination on surfaces of silicon wafers.
 - It can perform sampling nano metal contamination from the surface and sides (bevel parts) of silicon wafers.
 - Able to collect contamination of both hydrophobic and hydrophilic wafer surfaces.
- * Please note that bevel parts are when hydrophobic wafers only.
- * Applied to hydrophilic surface: SC-8150 and SC-9100 only.
- Can sample wafers made of materials other than silicon and wafers whose surface has been roughened by bulk etching. (such as SiC, GaN, sapphire compounds, the surface on blanket film wafer).
 - Possible to recover ions other than heavy metals.
 - Supply of recovery liquid and suction of recovery liquid after sampling are performed automatically (SC-3000 and SC-9000 only).
 - There is no specific skills needed of the operator as the sampling process is performed by the device, and everyone can operate it easily.

二、 Appearance Pictures of SC Series Products



SC-3100



SC-9100

NAS 有限会社NAS技研
GIKEN

SC-9200

簡易型微量金属汚染物質回収装置
Semi-Automated Recovery System of Nano Contaminants

保持具洗浄台
Auto clean stand for liquid holders

The advertisement for the SC-9200 features a dark blue background with a glowing network pattern. On the left is a large image of the SC-9200 instrument, which is white and has a red 'EMO' button. On the right is a smaller inset image showing a close-up of the 'Auto clean stand for liquid holders', which is a white ceramic or plastic component mounted on the machine.

SC-9200

三、SC Series Product Comparison

Device Name	SC-3100	SC-9100	SC-9200
Operation	PC (*3)		
Attaching / Detaching Liquid Holders	Auto		
Supply of Sampling Liquid	Auto		
Collection of Sampling Liquid	Auto (*4)	Auto	
Basic Sampling Pattern	Ring-shaped, Fan-shaped, Fixed, Radius, Arc		
Additional Sampling Pattern (*1)	Side (Bevel), Rectangle, Circular Segment		
Orientation Flat (*2)	Added to sampling pattern of Ring-shaped, Fixed Radius, Side (Bevel)		
Auto Cleaning of Liquid Holders	—		○
Sucking-Up Type Collection of Liquid		○	
Sampling of Hydrophilic Surface	—	○	
Size (W*D*H)(mm)	600*494*600	600*494*790	690*550*790
Weight	35Kg	50Kg	55Kg
Recommended Environment	Inside Clean Draft		
Utilities	AC-100-240V, DIW, CDA	AC-100-240V, DIW, N2, CDA	

*1-4: Those options and PC will be quoted separately

四、The Configuration of VPD BOX-300-5M (Vapor Phase Decomposition Box)

- A compact device that uses the natural vaporization of HF to VPD the oxide film and nitride film on the silicon wafer to make the wafer surface hydrophobic.
- PTFE and PVDF are used where the acid solution and acid atmosphere come into contact.
- Please use VPDBOX in combination with SC series.

五、Appearance Pictures of VPD BOX-300-5M Product

